

### **REMARKS**

Claims 1-8 remain in this application. Claims 1-4, 7 and 8 have been amended to better define Applicant's invention and to define over the art. All claims are rejected as anticipated by Inokuchi (U.S. Patent 6,259,960). Applicants respectfully traverse this rejection.

The Examiner, in the Office Action, page 4, lines 1-8, states that Inokuchi shows an outline view of the wafer in Fig. 73A and positional information of the foreign objects in the format shown in Fig. 73B. He finds this equivalent to displaying the coordinate information of the foreign objects and their vicinity field.

Furthermore, the Examiner states that Inokuchi shows moving the foreign objects to the center of the screen, because the coordinates of the optical microscope is usually different from that of the review SEM, referring to Fig. 74A-C.

However, Inokuchi does not show displaying an area indicating the field of view located within the vicinity area displaying the coordinates of the faults or foreign objects which were obtained by said another wafer or mask inspecting apparatus, and moving the field of view by moving the area indicating the field of view within the vicinity area by using a pointing device. In other words, the display shown in Fig. 2 (see enclosed copy) has a section which displays the vicinity area 24. Within area 24 is an area 26 indicating the field of view. Also displayable are the coordinates 25 of a defect. The pointer 23 (cursor) can be placed over the area 26 to drag it to the location of the defect, if the defect is not centered.

Inokuchi only shows moving the faults or objects themselves to the center of viewing of the screen, and therefore does not display an area showing the field of view of the electron microscope within the vicinity area displaying the coordinates of the faults obtained by any other inspecting apparatus. Nor does it show a pointer or cursor for moving the field of view within the vicinity area.

Applicants do not believe the present application is obvious over Inokuchi.

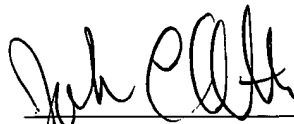
In view of the above, this application is now in condition for allowance, prompt notice of which is respectfully solicited.

The Examiner is invited to call the undersigned at (202) 220-4200 to discuss any information concerning this application.

The Office is hereby authorized to charge any additional fees under 37 C.F.R. § 1.16 or § 1.17 or credit any overpayment to Deposit Account No. 11-0600.

Respectfully submitted,

Date: May 21, 2004



John C. Altmiller  
Registration No. 25,951

KENYON & KENYON  
1500 K Street, N.W., Suite 700  
Washington, D.C. 20005  
Tel.: (202) 220-4200  
Fax.: (202) 220-4201  
492953\_1.DOC